

mirao™ 52-e

Electromagnetic Deformable Mirror

Technical Specifications

mirao's patented technology, plug-n-play installation, built-in protection (voltage clipping/temperature) and powerful API for C/C++ programmers make it the ideal choice for researchers developing innovative ophthalmic applications using adaptive optics. Even more, mirao is optimized to function with our **HASOTM4 first** wavefront sensors and **WaveTune™** control software.

Package contents:

- deformable mirror
- plug-n-play electronic control unit and connection cables
- API with examples, and control software

Number of actuators Maximum generated wavefront (PV) Surface quality (RMS active flat) Wavefront quality (RMS active flat) Integrated tip/tilt correction Spatial frequency correction Effective diameter Linearity Hysteresis Actuator input voltage Coatings Power consumption

Dimensions / Weight (mirror unit only)

Connectivity / Compatibility

52 50 µm (tilt) 0.01 µm $0.02 \, \mu m$

Main specifications

Zernike orders up to 6

15 mm > 95% < 2%

Yes

±1V max in each of the 52 channels

Sum of absolute voltages < 25 V

Protected silver 50 W max.

64 x 64 x 23 mm / 350 g USB 2.0 / Windows® 7 and 10

Zernike order Maximum peak-to-valley (PV) wavefront generation \pm 50 μm \pm 50 μ m ± 30 µm ± 30 µm \pm 40 μ m ± 10 µm ± 25 um ± 10 µm ± 25 µm ± 15 µm ± 8 µm ± 8 µm

Zernike mode quality:

RMS residual wavefront error: max 0.020 µm

(generation of any Zernike mode of order <5 with an amplitude set at 20% of total dynamic range)

± 8 µm



± 15 um